



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants

: Nicolas Demange et al.

Filed

July 15, 2003

Application No.

10/621,262

For

METHOD OF FABRICATING A FERROELECTRIC

STACKED MEMORY CELL

Docket No.

: 854063.523C1

Date

: November 3, 2003

Mail Stop Missing Parts Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents:

In accordance with 37 C.F.R. §§ 1.56 and 1.97 through 1.98, applicants wish to make known to the Patent and Trademark Office the references set forth on the attached Form PTO-1449. This application is a Continuation in Part and relies, under 35 U.S.C. § 120, on the earlier filing date of prior Application No. 09/911,637, filed July 23, 2001, which is a divisional of prior Application No. 09/365,187, filed August 2, 1999, now US Patent No. 6,300,654. The references listed on the attached Form PTO-1449 were submitted to and/or cited by the Patent and Trademark Office in this prior application and, therefore, are not required to be provided in this application. If the Examiner wishes, copies will be provided upon request. As to any reference supplied, applicants do not admit that it is "prior art" under 35 U.S.C. §§ 102 or 103, and specifically reserve the right to traverse or antedate any such reference, as by a showing under 37 C.F.R. § 1.131 or other method. Although the aforesaid references are made known to the Patent and Trademark Office in compliance with applicants' duty to disclose all information they are aware of which is believed relevant to the examination of the above-identified application, applicants believe that their invention is patentable.

Please acknowledge receipt of this Information Disclosure Statement and kindly make the cited references of record in the above-identified application.

Applicants believe this Information Disclosure Statement has been timely filed, however, the Commissioner is authorized to charge any fee due by way of this Information Disclosure Statement to our Deposit Account No. 19-1090.

Respectfully submitted,

Nicolas Demange et al.

Seed Intellectual Property Law Group PLLC

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Enclosures:

Form PTO-1449

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Sheet <u>1</u> of <u>1</u>

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* EXAMINE		nitial if reference consider	ed, v	vhether or not	criteria is in con	nfo	rmance with MPEP 609. Draw	line thro	ugh ci	tation if not in			
* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).												ļ	